

The International Conference on Instrumentation for Colliding Beam Physics (INSTR 2014)

CLIC Vertex Detector R&D



Sophie Redford

on behalf of the CLIC Detector and Physics Collaboration





- Linear electron-positron collider
- $\sqrt{s} = 3$ TeV (staged construction)
- High luminosity: 10³⁴ cm⁻²s⁻¹
- Small bunch size: $\sigma_{xyz}(40 \text{ nm}, 1 \text{ nm}, 44 \mu \text{m})$
- Beam structure:





Detector environment

- Beamstrahlung creates high particle rate 'beam induced backgrounds'
 - most at low angle, low p_T, constrained by B field
- Inner radius of vertex detector restricted by particle density





The CLIC detector



Precision physics in a challenging environment: broad programme of R&D

Highly granular particle flow calorimetry, using tungsten absorber

5.5 m diameter cryostat for superconducting solenoid, B field 4-5 T

Instrumented steel return yoke

Complex forward region

Vertex detector requirements



Efficient tagging of heavy quarks through a precise determination of displaced vertices



Multi-layer barrel and endcap pixel detectors

- ▶ 560 mm in length
- Barrel radius from 30 mm to 60 mm



- Single point resolution of 3 µm
- Material budget of < 0.2% of a radiation length per layer
- No active cooling elements use forced air flow cooling
- Limit the power dissipation to 50 mW/cm² in sensor area
- Hit time slicing of 10 ns

Olympic programme of R&D



Geometry optimisation studies



Double-sided layers

Comparison of 5 single-sided layers and 3 double-sided layers



- Similar flavour tag performance for two considered layouts
- Increasing the material has a larger impact than the layout



Thin sensor assemblies

- Hybrid planar pixel technology
- Ultimate goal: 50 µm sensor on 50 µm ASIC
- 25 µm pitch
- Thin edge sensors using Through-Silicon-Vias





50 μm thick silicon wafer

TSVs:

- Vertical electrical connection no wire bonds
- Sensors buttable on all sides better tiling



- 60 μm hole diameter
- Wafer thinned to 120 µm
- 5 µm copper layer for TSV



Testbeam analysis

- Thin sensors (50 300 μm) bonded to normal Timepix chips
- One 100-on-100 µm assembly
- Data recorded at DESY: 5.6 GeV electron beam





100 µm thick sensor - low charge sharing



Sensor calibration

Global calibration

- Calibrate TOT values by measuring response to photons of known energy
- Accounts for non-linearities
- Calibration aligns Landau's and improves the resolution: 4.8 µm → 4.7 µm

No calibration



2 hit clusters global calibration EtaCorrection

0

 -0.0002513 ± 0.0000162

 0.00471 ± 0.00001

0.05

Y residual (mm)



Sources and X-ray fluorescence

Preliminary

0.1

Readout ASIC: CLICpix

- The CLICpix ASIC: a fast, low power readout chip with 25 µm pitch
- Implemented in 65 nm CMOS technology
- 4-bit time and energy measurements for each pixel
- Supports power-pulsing and data compression



CLICpix characterisation

TOT gain distribution





- Time Over Threshold gain distribution
- Uniform gain across the whole matrix
- Gain variation is 4.2% r.m.s. (for nominal feedback current)

- Matrix equilisation
- Calibrated spread is 0.89 mV (about 22 e⁻) across the whole matrix
- (Expect a signal of ~thousands of electrons in 50 µm sensor)

Power-pulsing strategy

- Power pulse CLICpix ASIC to achieve dissipation <50 mW/cm² in the sensor area
- Analog electronics can be turned off: $2 \text{ W/cm}^2 \rightarrow 2 \text{ mW/cm}^2$
- Digital electronics in idle except during readout: 100 mW/cm² \rightarrow 13 mW/cm²



Power delivery

- Power ladders from each end of the barrel:
 - constant current sources, low dropout regulators, silicon capacitors



Material budget:

- Aluminium flex cables and silicon capacitors reduce material
- Powering adds $0.1\% X_0$ per layer. Projected: < $0.05\% X_0$

Power-pulsing lab tests



Controlled current source

Analogue:

- Voltage drop < 20 mV
- Measured average power dissipation < 10 mW/cm²

Digital:

Measured average power dissipation < 35 mW/cm²

Total dissipation: < 50 mW/cm²



Air-flow cooling

- Total heat load after power-pulsing ~470 W
- Cooling provided by forced air-flow:
 - Dry air cooling at 0°C
 - ► Low material: radiation length of air ~310m





Warm air

Air-flow simulations





- Mass flow: 19.9 g/s
- Avg. velocity in barrel: 6.3 m/s
- Silicon temperature below 40°C
- Conduction not taken into account



Mechanical support structures

- Develop and characterise low-mass carbon-fibre structures
- Stave dimension 1.8 mm*26 mm*280 mm
- Goal material per layer: 0.05% X₀

Rohacell core (PMMA)

Full sandwich stave



Cross braced staves



Skin stave

Stave mechanical characterisation

 Measure the flexural stiffness (resistance to bending) of the staves over span of 180 mm







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Measurements	6.95 N/mm	2.24 N/mm	3.3 N/mm	2.96 N/mm	2.23 N/mm
Simulations	6.95 N/mm	2.35 N/mm	-	-	2.30 N/mm

Next: measure the amplitude of stave vibration in air flow

Thermo-mechanical test bench







- Measure wind speeds, stave temperatures, stave vibrations
- Allows validation of simulations



Thermal camera



Simulation



Test bench results



 Simulation in good agreement with measurements

Flow direction



Summary

- CLIC machine and physics requirements place challenging demands on the vertex detector
- Initial layouts are being refined
- Active R&D into thin sensor assemblies and readout chips
- Powering, cooling and mechanical supports under design and test

The CLIC vertex detector: precision at high energy



Thanks for your attention!